

COOLING STRUCTURE FOR PLASMA LIGHTING SYSTEM

TECHNICAL FIELD

The present invention relates to a plasma lighting system using
5 microwave, and more particularly, to a cooling structure for a plasma lighting
system which can easily cool inner heat generating components of the plasma
lighting system.

BACKGROUND ART

10 In general, a plasma lighting system using microwave is a device for
obtaining visible rays or ultraviolet rays by adding microwave to an
electrodeless light bulb. The lighting system has a long life span when
compared with a general incandescent lamp or a fluorescent lamp, and has an
excellent lighting effect.

15 Figure 1 is a longitudinal sectional view showing a conventional plasma
lighting system.

The conventional plasma lighting system comprises: a case 1; a
magnetron 3 arranged in the case 1 for generating microwave; a waveguide 5
arranged in the case 1 for transmitting the microwave generated from the
20 magnetron 3; a light bulb 7 having lighting material therein and protruded in
front of the case 1 for generating light; a mesh screen 9 fixed at an exit of the
waveguide 5 for shielding microwave and passing light; and a reflective mirror
11 fixed to a frontal surface of the case at a circumference of the mesh screen

9 for reflecting the light generated at the bulb 7 forward.

A high voltage generator 13 for supplying high voltage to the magnetron 3 is installed inside of the case 1.

The waveguide 5 is provided with a shaft hole 5a at the center thereof, and a rotational shaft 10 for rotating the light bulb 7 passes the shaft hole 5a. Also, a bulb motor 8 to which the rotational shaft 10 is engaged is installed at the rear side of the waveguide 5 to rotate and cool the light bulb 7.

Especially, a blowing unit 14 for cooling the magnetron 3, the high voltage generator 13, and the bulb motor 8 are installed at the rear side of the case 1. The blowing unit 14 includes a fan housing 15 corresponding to a passage where external air is introduced in the case, a fan 16 provided in the fan housing 15, and a fan motor 17 for rotating the fan 16.

In said plasma lighting system, when a driving signal is inputted to the high voltage generator 13, the high voltage generator 13 boosts an AC power source from the exterior and supplies the boosted high voltage to the magnetron 3.

The magnetron 3 resonates by the high voltage supplied from the high voltage generator 13 and generates microwave of high frequency. The generated microwave is transmitted to the inner portion of the mesh screen 9 through the waveguide 9 to discharge the lighting material sealed in the light bulb 7, thereby generating light having a unique emit spectrum.

The light generated from the bulb 7 is reflected forward through the reflection mirror 11 and illuminates a lighting space.

In the meantime, when the plasma lighting system is operated, the fan motor 17 is together operated. At this time, by the fan 16 operated by the fan motor 17, external air of the case 1 passes a suction port 15a and two discharge ports 15b and 15b' of the fan housing 15, cools the magnetron 3 and the high voltage generator 13, and is discharged out through an outlet port 1a formed in front of the case 1.

However, in the conventional plasma lighting system, since the two discharge ports 15b and 15b' provided to the fan housing 15 are formed to have the same area, the magnetron 3 which generates heat relatively higher than any other parts can not be effectively cooled.

Accordingly, when high heat generating components such as the magnetron 3 are not sufficiently cooled, a durable life span is shortened or a performance is greatly degraded. To solve this, entire capacities of the fan and the fan motor have to be increased to sufficiently cool the high heat generating components.

Also, the conventional plasma lighting system has a structure that external air is sucked from the rear side of the case 1 and discharged to the frontal side of the case 1, so that warm air which has cooled various kinds of components is discharged to the lighting space to provide uncomfortable feeling to a user. To solve this, that is, to discharge the air from the frontal side of the case 1 to the other side, an additional discharge duct is required.

DISCLOSURE OF THE INVENTION

Therefore, it is an object of the present invention to provide a cooling structure for a plasma lighting system which can effectively cool heat generating components of high temperature such as a magnetron to prolong
5 life span of the components and improve a performance of the system by making a discharge flow rate different according to heat generation amounts of the components and a design condition without unnecessarily enlarging a fan capacity.

To achieve these objects, there is provided a cooling structure for a
10 plasma lighting system including a fan housing having at least two discharge ports having different discharge flow rates for cooling heat generating components in the case by introducing external air in the case

In the discharge ports of the fan housing, prolonged ducts for guiding the discharge air to each heat generating component are provided.

15 At least one prolonged duct is composed of a distribution duct having at least two discharge ports in order to intensively cool at least two specific components of the heat generating components.

According to one preferred embodiment of the present invention, the case is provided with the fan housing at the rear side thereof to introduce
20 external air, and provided with a case outlet for discharging air that cooled the heat generating components at the frontal side thereof. At the case outlet, a discharge guide member is formed with a round shape.

According to another embodiment of the present invention, the case is

formed with a double cylinder structure having an inner case and an outer case. The external air circulating by the fan housing is introduced into the rear surface of the inner case, passes the inside of the inner case, flows to the inside of the outer case, and is discharged to the rear surface discharge port of the outer case.

According to still another embodiment of the present invention, a plurality of discharge ducts for discharging air which passed the inside of the case are provided at an outer surface of the case by being connected to the case.

Herein, the case includes a first discharge port connected to a frontal portion of the discharge duct, and a second discharge port connected to a middle portion of the discharge duct.

According to still another embodiment of the present invention, the discharge duct has first discharge port at the rear portion thereof, and second discharge port at the lateral portion thereof.

According to still another embodiment of the present invention, the case has a plurality of radiation fins protruded toward the inner side of the discharge duct.

According to still another embodiment of the present invention, a plurality of radiation fins are formed at the outer surface of the case.

Since a discharge flow rate is different according to heat generation amounts of the components and a design condition, a system according to the present invention can effectively cool the heat generating components of high

temperature such as the magnetron, thereby prolonging life span of the components and improving a performance of the system without unnecessarily enlarging a fan capacity.

Also, in the present invention, since air which has cooled the heat
5 generating components in the case is discharged to the rear side of the case, warm air is not discharged to a lighting space, thereby not causing uncomfortable feeling to the user and enhancing convenience.

BRIEF DESCRIPTION OF THE DRAWINGS

10 Figure 1 is a longitudinal sectional view showing the conventional plasma lighting system;

Figure 2 is a longitudinal sectional view showing a plasma lighting system according to the first preferred embodiment of the present invention;

15 Figure 3 is a longitudinal sectional view showing a plasma lighting system according to the second preferred embodiment of the present invention;

Figure 4 is a sectional view of a case taken along line A-A of Figure 3;

Figure 5 is a longitudinal sectional view showing a plasma lighting system according to the third preferred embodiment of the present invention;

20 Figure 6 is a sectional view of a case taken along line B-B of Figure 5;

Figure 7 is a cross-sectional view of the case according to the fourth preferred embodiment of the present invention;

Figure 8 is a longitudinal sectional view showing a plasma lighting

system according to the fifth preferred embodiment of the present invention;

Figure 9 is a sectional view of the case taken along line C-C of Figure 8;
and

Figure 10 is a cross-sectional view of the case according to the sixth
5 preferred embodiment of the present invention.

MODES FOR CARRYING OUT THE PREFERRED EMBODIMENTS

Hereinafter, the cooling structure of a plasma lighting system according
to the present invention will be explained with reference to the attached
10 drawings.

Figure 2 is a longitudinal sectional view showing a plasma lighting
system according to the first preferred embodiment of the present invention.

Referring to Figure 2, in the case 50, there are provided a magnetron 61
for generating microwave; a waveguide 63 for transmitting the microwave
15 generated from the magnetron 61; a high voltage generator 65 for providing a
high voltage to the magnetron 61; and a bulb motor 66 for rotating and cooling
a light bulb 68.

Herein, the waveguide 63 is located at the inner center portion of the
case 50. At both sides of the waveguide 63, the magnetron 61 and the high
20 voltage generator 65 are respectively located, and at the rear side of the
waveguide 63, the bulb motor 66 is located.

In front of the case 50, there are provided the light bulb 68 for
generating light by the microwave, a mesh screen 70 for shielding the

microwave and passing light, and a reflection mirror 72 for reflecting the light generated at the bulb 68 forward.

A blowing unit 80 for cooling heat generating components such as the magnetron 61, the high voltage generator 65, and the bulb motor 66 is installed
5 at the rear side of the case 50.

The blowing unit 80 includes a fan housing 81 corresponding to a passage where external air is introduced in the case 50, a fan 83 provided in the fan housing 81, and a fan motor 85 for rotating the fan 83.

The fan housing 81 is provided with a suction port 81a at the frontal
10 center portion of the fan housing 81. The fan 83 is located at the inner side of the suction port 81a. Especially, the fan housing 81 has a first discharge port 81b and a second discharge port 81c for respectively discharging air toward the magnetron 61 and the high voltage generator 65.

Herein, since the magnetron 61 generates heat of higher temperature
15 than the high voltage generator 65, larger discharge flow rate has to be formed at the place where the magnetron 61 and the bulb motor 66 are located. According to this, a sectional area S1 of the first discharge port 81b is formed to be larger than a sectional area S2 of the second discharge port 81c.

It is possible that a ratio of the sectional areas of the first discharge port
20 81b and the second discharge port 81c is 6:4.

At the first and second discharge ports 81b and 81c of the fan housing 81, prolonged ducts 90 and 91 for guiding discharge air to the heat generating components such as the magnetron 61 and the high voltage generator 65 are

respectively formed.

The prolonged duct 90 connected from the first discharge port 81b to the magnetron 61 is composed of a distribution duct 95 having a first sub discharge port 96a and a second sub discharge port 97a in order to intensively
5 cool the magnetron 61 and the bulb motor 66, respectively.

Also, in order to more intensively cool the magnetron 61, the first sub discharge port 96a of the distribution duct 95 that intensively discharges air to the magnetron 61 is formed to be larger than the second sub discharge port 97a that intensively discharges air to the bulb motor 66.

10 That is, the distribution duct 95 is composed of a main duct 96 having the first sub discharge port 96a for making discharge flow rate great, and a diverged duct 97 divided from the main duct 96 and having the second sub discharge port 97a.

In the meantime, in front of the case 50, a case discharge port 50a for
15 discharging air that has cooled the heat generating components such as the magnetron 61 is formed. The case discharge port 50a provided with a discharge guide member 55 for guiding the discharged air to the lateral side direction of the case 50 is formed with a round shape.

In the meantime, various kinds of the fan 83 provided in the fan housing
20 80 such as a sirocco fan, an axial fan, etc. can be installed according to the design condition. Also, even if the prolonged ducts 90 and 91 are formed at the fan housing 80 as a single body or separated ones.

Also, the number and a direction of the discharge ports 81b and 81c of

the fan housing 81, the prolonged ducts 90 and 91, and the distribution duct 95 can be constructed differently according to locations of the heat generating components arranged in the case 50.

The cooling structure for the plasma lighting system according to the
5 first preferred embodiment of the present invention will be explained.

When a high voltage boosted from the high voltage generator 65 is supplied to the magnetron 61, the magnetron 61 generates microwave and radiates it to the inside of the mesh screen 70 through the waveguide 63. Also, lighting material in the bulb 68 is formed in plasma state by electric field due to
10 the microwave, thereby generating light and illuminating the lighting space.

Also, since the bulb motor 66 and the fan motor 85 are simultaneously operated with the high voltage generator 65, the bulb motor 66 cools the bulb 68 with rotating it and the fan motor 85 makes external air of the case 50 flow into the case 50 to cool the heat generating components such as the
15 magnetron 61, the high voltage generator 65, the bulb motor 66, and the fan motor 85.

In the meantime, in accordance with that the fan 83 is operated, external air introduced through the suction port 81a of the fan housing 81 intensively cools the magnetron 61, the bulb motor 66, and the high voltage generator 65
20 through the respective prolonged ducts 90 and 95 by the first and second discharge ports 81b and 81c.

Herein, since a sectional area of the first discharge port 81b is larger than that of the second discharge port 81c, larger amount of external air is

provided to the distribution duct 95 toward the magnetron 61 and the bulb motor 66. Also, since the distribution duct 95 is divided into two first and second sub discharge ports 96a and 97a, the external air is intensively supplied to the magnetron 61 and the bulb motor 66.

5 Like this, the heat generating components in the case 50 can be intensively cooled more efficiently by providing more external air to the magnetron 61 that relatively generates high heat and by forming the distribution structure to intensively supply the external air to the specific components such as the magnetron 61 and the bulb motor 66.

10 Accordingly, in the present invention, more external air is provided to the heat generating components which are relatively overheated, so that a cooling is efficiently performed, thereby prolonging a life span and enhancing a reliability of the device.

15 The air that has cooled the inner components of the case 50 is discharged out through the case discharge port 50a formed in front of the case 50. At this time, the discharge air is discharged toward the outer direction of the case 50 by the discharge guide member 55 formed in front of the case discharge port 50a.

20 Hereinafter, the same construction parts with those of the first preferred embodiment will be given the same reference numerals and their explanations will be omitted for the simplicity purpose.

Figure 3 is a longitudinal sectional view showing a plasma lighting system according to the second preferred embodiment of the present invention,

and Figure 4 is a sectional view of a case taken along line A-A of Figure 3.

In the aforementioned first preferred embodiment, the case is constructed to discharge air to the frontal side thereof. However, in the second preferred embodiment of the present invention, the case 50 is constructed to
5 discharge air to the rear side thereof.

That is, in the second preferred embodiment, the case 50 is formed with a double cylinder structure having an inner case 51 and an outer case 52. A discharge path 50b connected to the outer case 52 is formed in front of the inner case 51, and a discharge port 56a for discharging air outside is formed at
10 the rear surface of the outer case 52.

Accordingly, external air introduced into the inner case 51 by the fan 83 cools the heat generating components such as the magnetron 61 in the case 51, flows toward the inside of the outer case 50 through the discharge path 50b, and is discharged out through the discharge port 56a of the outer case 50.

15 In the meantime, at the discharge port 56a of the outer case 52, a filtering member for preventing foreign substances including insects is preferably installed at the discharge port 56a of the outer case 52.

In the second preferred embodiment of the present invention, by discharging cooled air toward the rear of the case 50, user's convenience can
20 be enhanced, and by providing the discharge passage connected to the outer case 52, air discharge is smoothly performed.

Figure 5 is a longitudinal sectional view showing a plasma lighting system according to the third preferred embodiment of the present invention,

and Figure 6 is a sectional view of a case taken along line B-B of Figure 5.

In the aforementioned second preferred embodiment, the case is composed of a double structure and air is discharged to the rear side of the case. However, in the third embodiment of the present invention, air is
5 discharged to the rear of the case 50 through the discharge port 56a of the discharge duct 56 prolonged at the outer surface of the case 50.

That is, said two discharge ducts 56 are provided at both sides of the case 50 and prolonged along the case 50 for discharging air that has passed the inside of the case 50 to the rear of the case 50 through the discharge port
10 of the duct.

Also, the case 50 includes a discharge path 50b connected to the frontal portion of the discharge duct 56 and a discharge opening 50c connected to the middle portion of the discharge duct 56.

Herein, whereas the discharge path 50b of the case 50 is formed as a
15 completely opened structure, the discharge opening 50c is formed as a grill structure composed of a plurality of holes by being cut from a part of the case 50, curved, and opened. At this time, a discharge direction of the discharge opening 50c of the case 50 is preferably formed toward the discharge port 56a of the discharge duct 56.

20 In the cooling structure of the plasma lighting system according to the third preferred embodiment of the present invention, the air which passes the inside of the case 50 is easily discharged out in a state that a construction of the case 50 is simplified and the flow resistance is minimized through the

discharge path 50b and the discharge opening 50c of the case 50.

Figure 7 is a cross-sectional view of the case according to the fourth preferred embodiment of the present invention.

The fourth preferred embodiment of the present invention is the same
5 with the third preferred embodiment except that an additional discharge port 50d for discharging air outside is formed at the lateral surface of the discharge duct 56.

The additional discharge port 50d is also preferably formed as the grill structure similarly to the discharge opening 50c of the case 50 in the third
10 preferred embodiment.

In the fourth embodiment of the present invention, air can be discharged more easily by magnifying the discharge passage of the discharge duct 56 and thereby minimizing a flow resistance.

Figure 8 is a longitudinal sectional view showing a plasma lighting
15 system according to the fifth preferred embodiment of the present invention, and Figure 9 is a sectional view of the case taken along line C-C of Figure 8.

In the fifth preferred embodiment of the present invention, similarly to the third embodiment, air is discharged to the rear of the case 50 through the discharge duct 56 prolonged to the outer surface of the case 50.

20 One different thing is that radiation fins 58 protruded from the outer surface of the case 50 are provided at the inside of the discharge duct 56. The radiation fins 58 can be formed toward a flow direction of the discharge air or orthogonal to the flow direction of the discharge air. Also, a shape and an

arrangement of the radiation fins 58 can be different according to a design condition or a necessity.

In the fifth embodiment of the present invention, a portion of heat generated in the case 50 is radiated outward through the radiation fins 58, and
5 the air discharged through the discharge duct 56 is contacted to the radiation fins 58, so that a contact area with air is enlarged, thereby enhancing an entire cooling efficiency of the system.

Figure 10 is a cross-sectional view of the case according to the sixth preferred embodiment of the present invention.

10 In the aforementioned third, fourth, and fifth embodiments, two discharge ducts 56 are formed at the outer surface of the case 50. However, in the sixth embodiment of the present invention, four discharge ducts 56 are formed at the outer surface of the case 50.

The discharge ducts 56 are located at the circumference surface of the
15 case 50 with predetermined intervals. Also, the number of the discharge ducts 56 can be variously constructed according the design condition even if the present invention is constructed as four discharge ducts.

Especially, a plurality of radiation fins 59 for easily radiating heat in the case 50 are formed at the outer surface of the case 50. The radiation fins 59
20 are preferably formed at the outer surface of the case 50 where the discharge duct 56 is not formed.

In the sixth embodiment of the present invention, four discharge ducts 56 are constructed, thereby reducing a discharge flow resistance of air. Also,

the plurality of radiation fins 59 are formed at the outer surface of the case 50, so that a cooling efficiency is enhanced.

INDUSTRIAL APPLICABILITY

5 In the cooling structure of the plasma lighting system according to the present invention, since a discharge flow rate is different according to a heat generation amount of the components and a design condition, a system can effectively cool the heat generating components of high temperature such as a magnetron, thereby prolonging life span of the components and improving a
10 performance of the system without unnecessarily enlarging a fan capacity.

Also, in the present invention, since air that has cooled the heat generating components in the case is discharged to the rear of the case, warm air is not discharged to the lighting space, thereby not causing uncomfortable feeling to the user and enhancing convenience.

15 It will be apparent to those skilled in the art that various modifications and variations can be made in the present invention without departing from the spirit or scope of the invention. Thus, it is intended that the present invention cover modifications and variations of this invention provided they come within the scope of the appended claims and their equivalents.